56th ANNUAL LASER DAMAGE SYMPOSIUM
Proceedings

LASER-INDUCED DAMAGE IN OPTICAL MATERIALS 2024

7–11 October 2024
San Ramon, California, United States

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Published by
SPIE

Proceedings of SPIE 0277-786X, V. 13190

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Please use the following format to cite material from these proceedings:
Author(s), "Title of Paper," in *Laser-Induced Damage in Optical Materials 2024*, edited by Christopher W. Carr, Detlev Ristau, Carmen S. Menoni, Michael D. Thomas, Proc. of SPIE 13190, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510680883
ISBN: 9781510680890 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time)
SPIE.org
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